



Docket No.: 49657-961

110921801
PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of

Kenji ITOGA, et al.

Serial No.: 09/769,490

: Group Art Unit: 2882

Filed: January 26, 2001

: Examiner: C. Kao

For: X-RAY EXPOSURE APPARATUS, X-RAY EXPOSURE METHOD, X-RAY MASK, X-RAY MIRROR, SYNCHROTRON RADIATION APPARATUS, SYNCHROTRON RADIATION METHOD AND SEMICONDUCTOR DEVICE

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
Washington, DC 20231

Dear Sir:

In accordance with the provisions of 37 C.F.R. 1.56, 1.97 and 1.98, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached form PTO-1449. It is respectfully requested that the references be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

This Information Disclosure Statement is being filed within three months of the U.S. filing date OR before the mailing date of a first Office Action on the merits. No certification or fee is required.

Each English language reference was cited in a corresponding foreign application search report or office action and its relevance discussed therein.

A copy of the foreign search report or office action is attached for the Examiner's information.

Respectfully submitted,

MCDERMOTT, WILL & EMERY


Stephen A. Becker
Registration No. 26,527

- 600 13th Street, N.W.
Washington, DC 20005-3096
- (202) 756-8000 SAB:mlw
- **Date: December 4, 2001**
- Facsimile: (202) 756-8087